

Wide-band Induction Acceleration in the KEK Digital Accelerator

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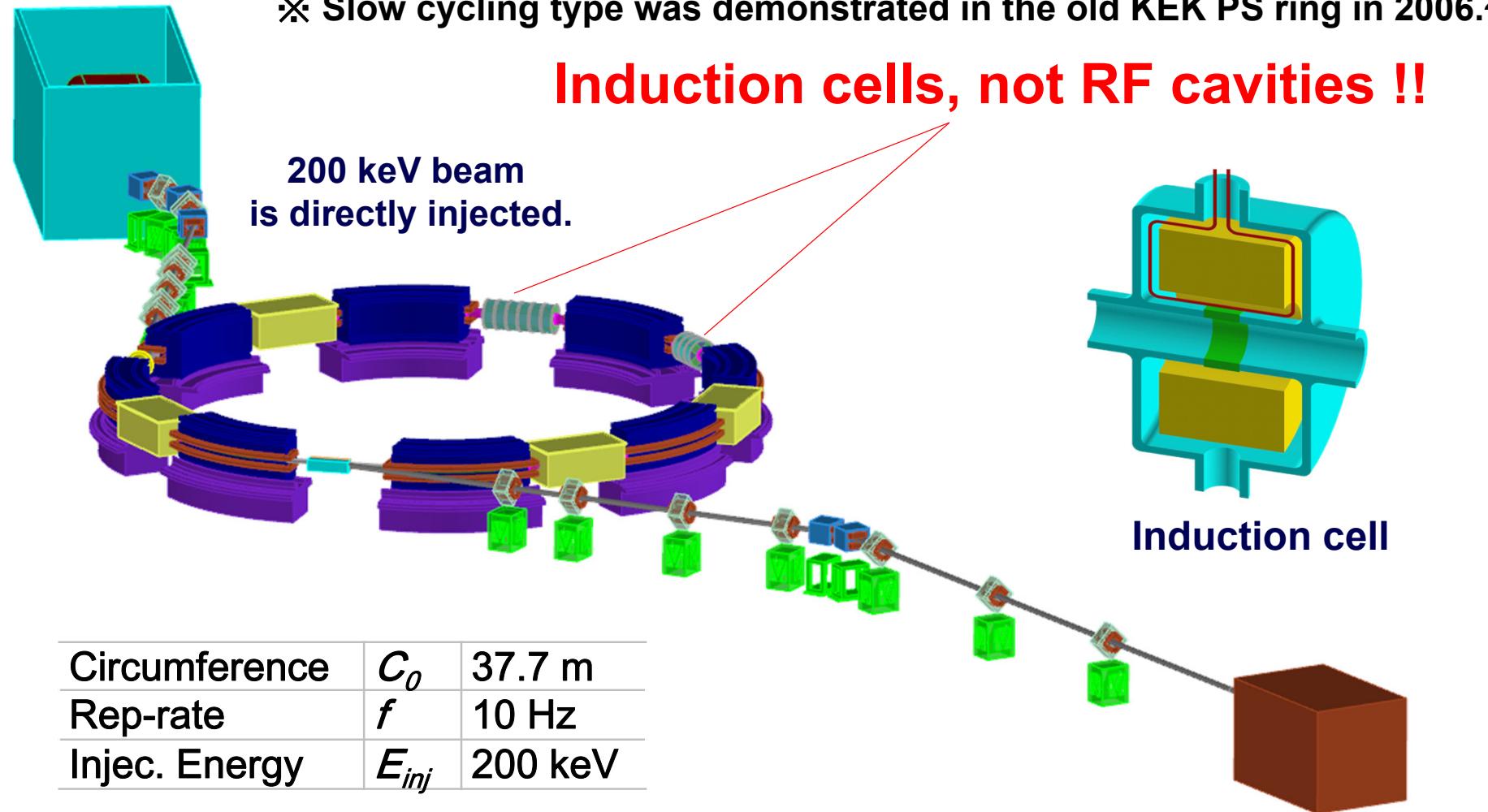
Contents

- ◆ What is induction synchrotron ?
- ◆ Three features of induction synchrotron
- ◆ Outline of KEK digital accelerator
- ◆ Wide band acceleration
- ◆ Novel beam handling
- ◆ Conclusion

What is Induction synchrotron ?

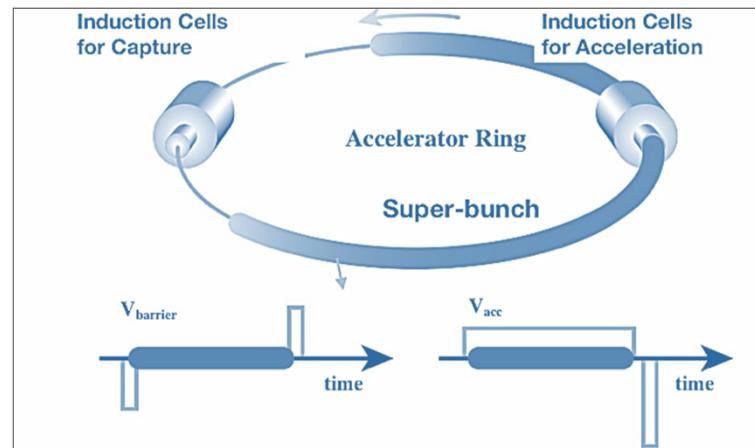
KEK digital accelerator (Wide-band fast cycling induction synchrotron)¹⁾

※ Slow cycling type was demonstrated in the old KEK PS ring in 2006.²⁾

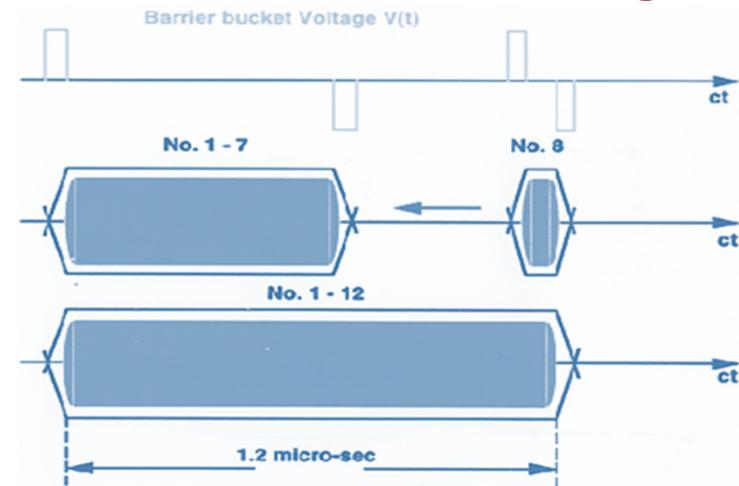


Three notable features of Induction synchrotron

Super-bunch acceleration¹⁾



Novel beam handling

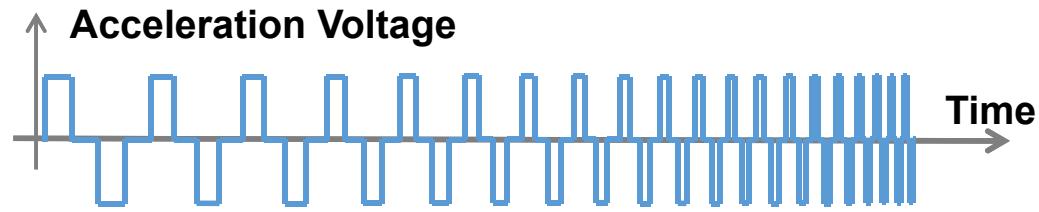


Wide-band acceleration²⁾

Advantages

Rev. frequency: 0 ~ a few MHz

Wide variety of ion species can be provided in a broad energy range.

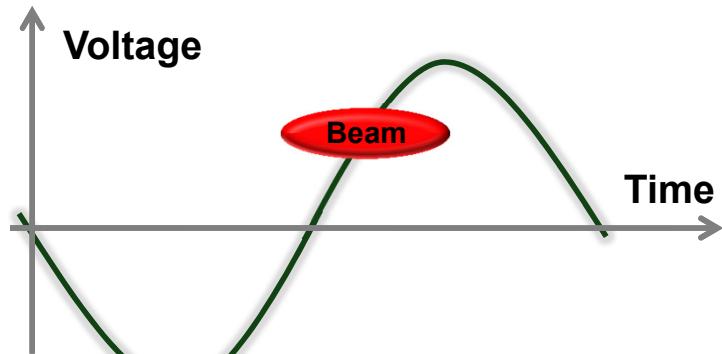


Disadvantages

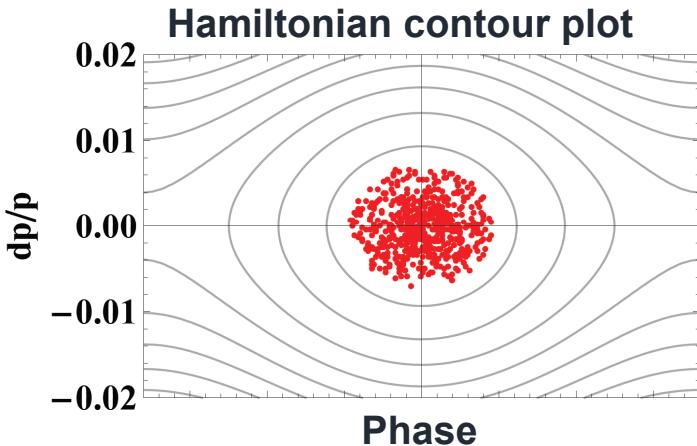
- Space charge limit & residual gas interactions in low energy region
- In small ring (~100 m), max. rev. frequency is limited by semiconductor switching of acc. volt..

RF acceleration & Induction synchrotron

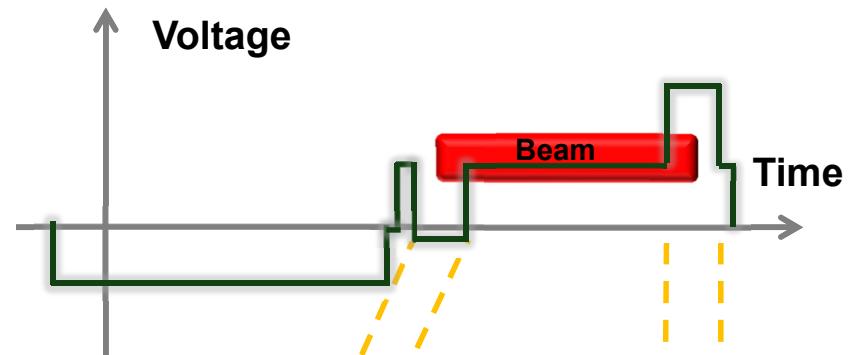
Conventional RF acceleration



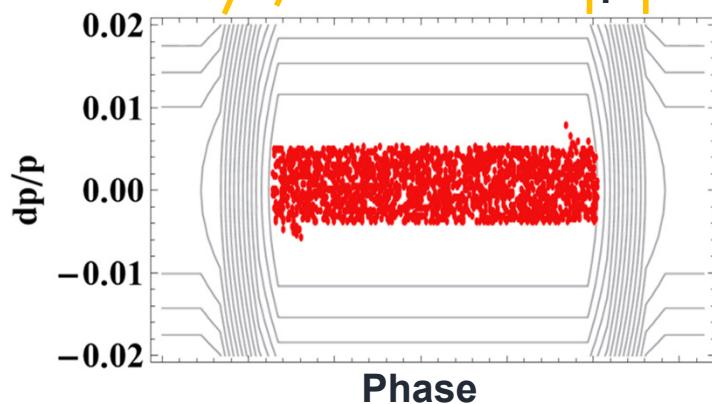
Confinement & Acceleration function are combined.



Induction acceleration

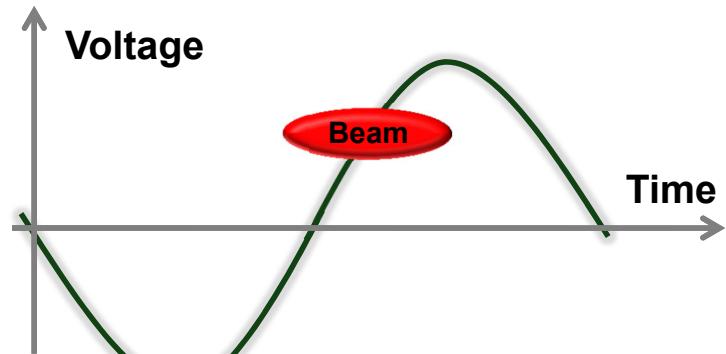


Hamiltonian contour plot

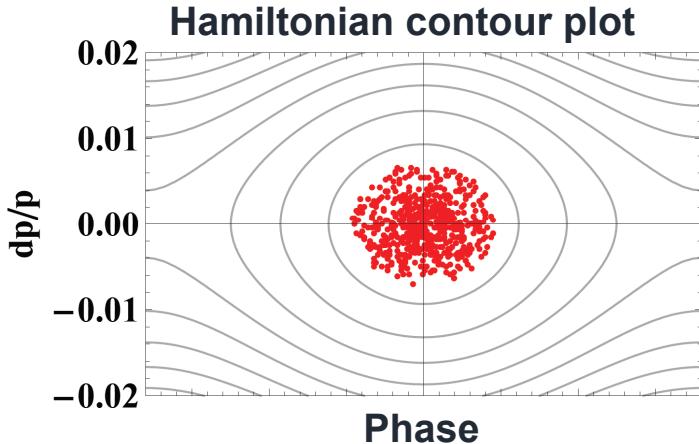


RF acceleration & Induction synchrotron

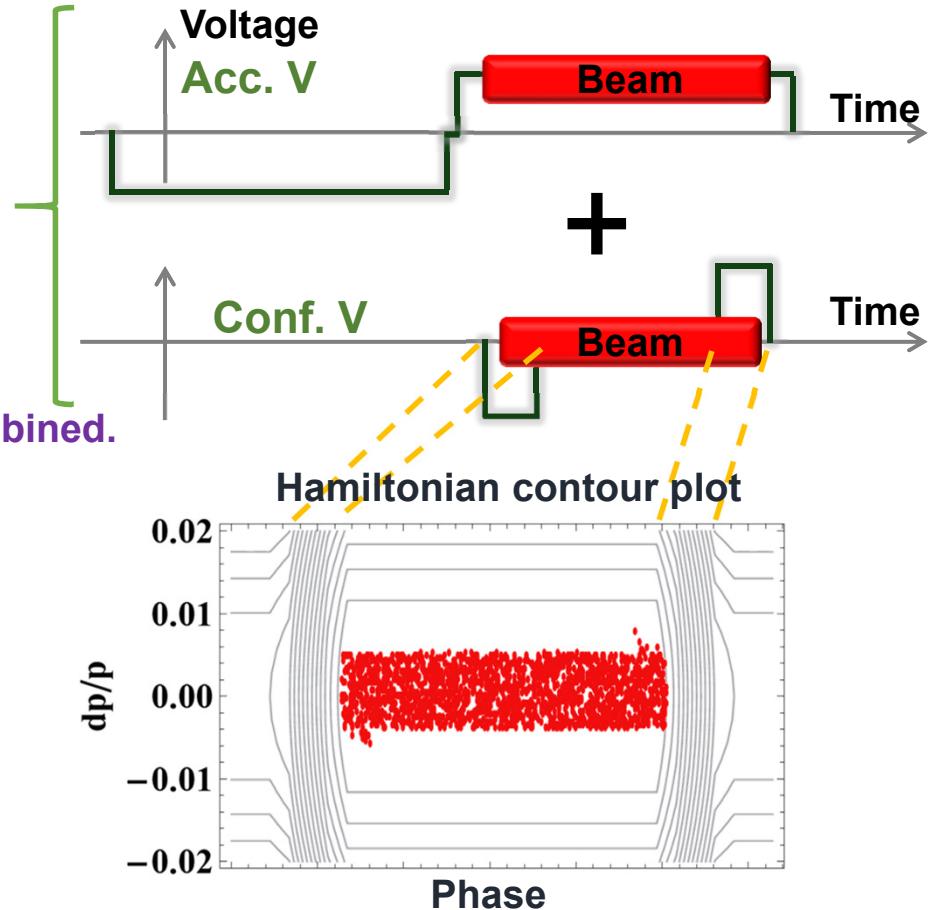
Conventional RF acceleration



Confinement & Acceleration function are combined.

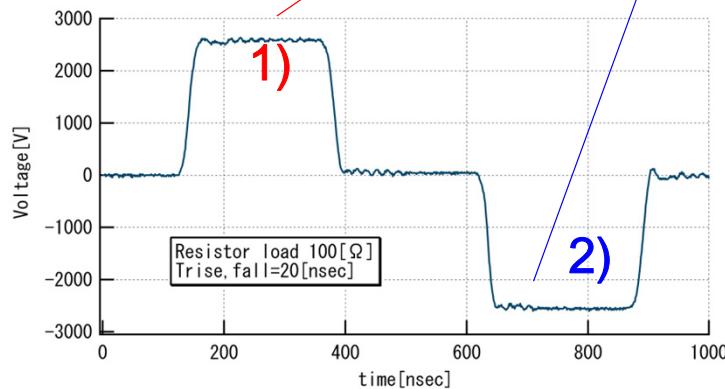
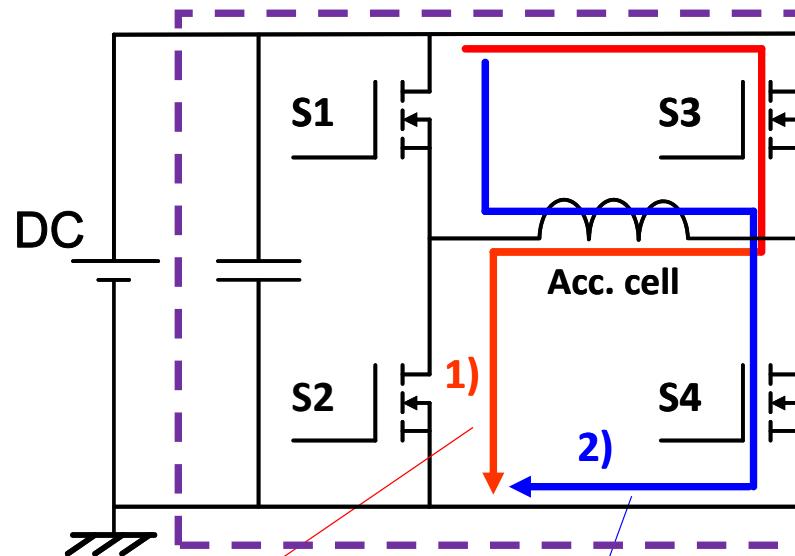


Induction acceleration

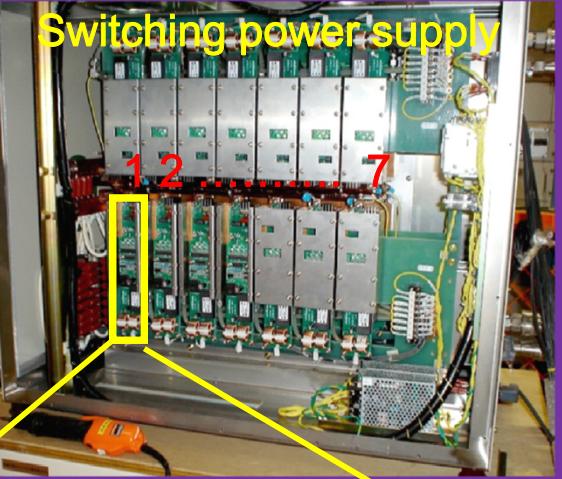


5 Separate function can creates a longer bucket \Rightarrow mitigating space charge effect.

Switching Power Supply for Induction cells



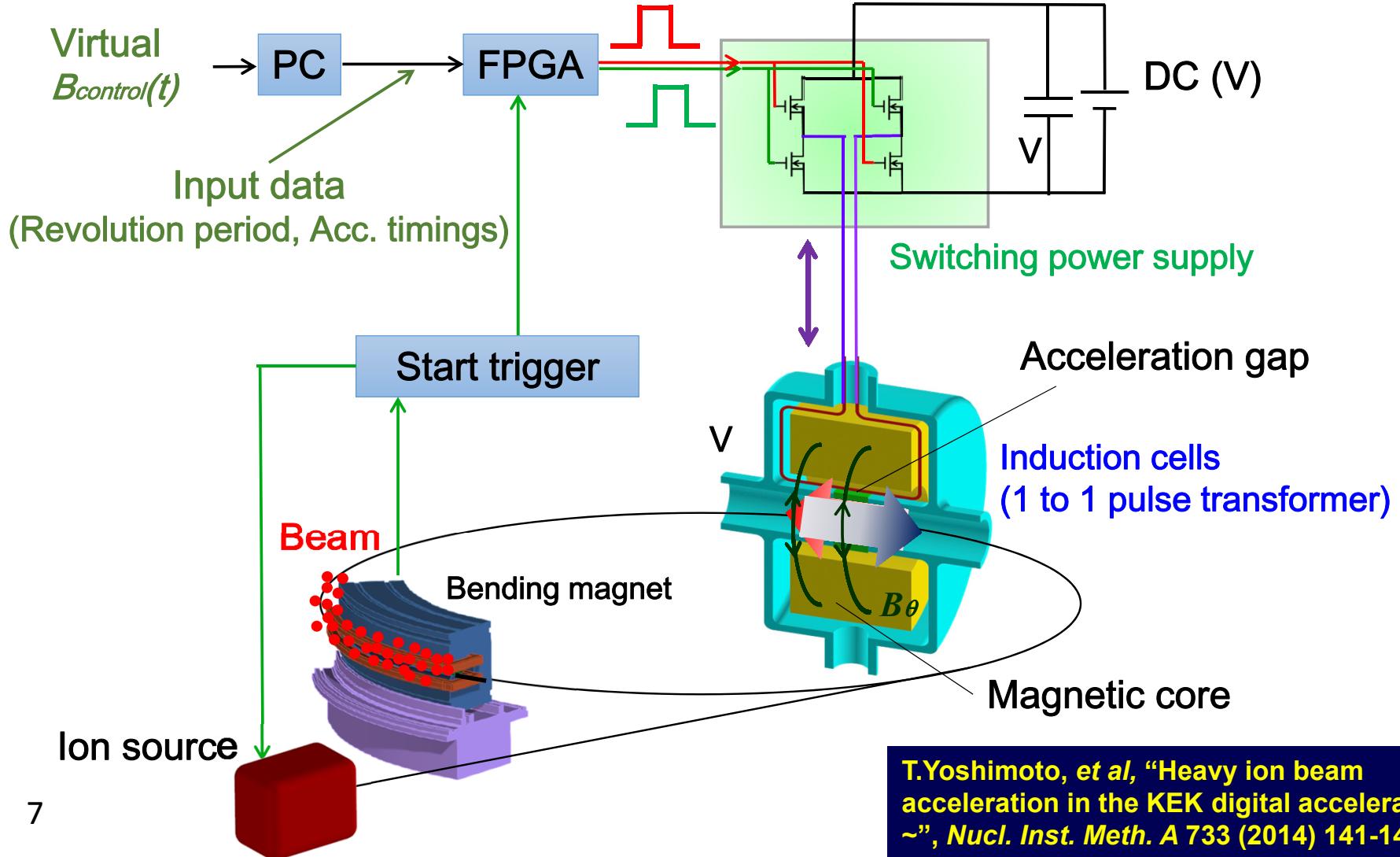
Waveform generated by switching power supply
(2.5kV, 20A, 1MHz)



Next generation of SPS: K.Okamura, *et al.*, MOPME068 in IPAC'14
"SiC-JFET Switching Power Supply toward for Induction Ring Accelerators"

Fully programmed control of KEK digital accelerator

In advance, all information for acceleration timings is load to FPGA.
Virtual $B(t)$ decides ideal revolution period and acc. timings.



How to generate confinement voltages

Reference signals: 12 μ s \rightarrow 1 μ s
 (which generate every ideal rev. period of beam)

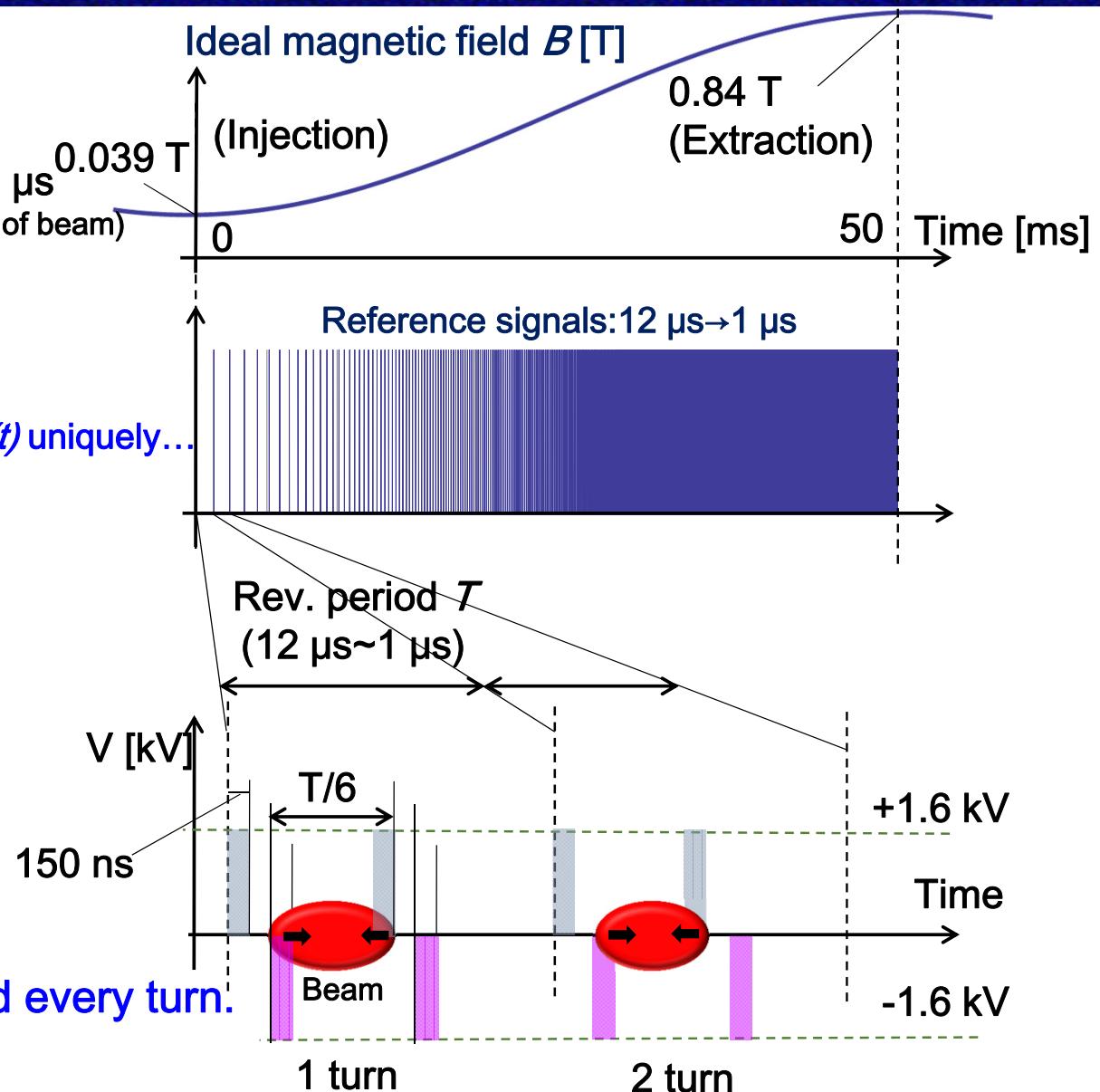
$$T(t) = \frac{C_0}{c} \sqrt{\frac{1+D}{D}}$$

$B(t)$ determines $T(t)$ uniquely...

$$D = \left\{ \left(\frac{Q}{A} \right) \left(\frac{e\rho}{m_0 c} \right) \right\}^2 B^2$$

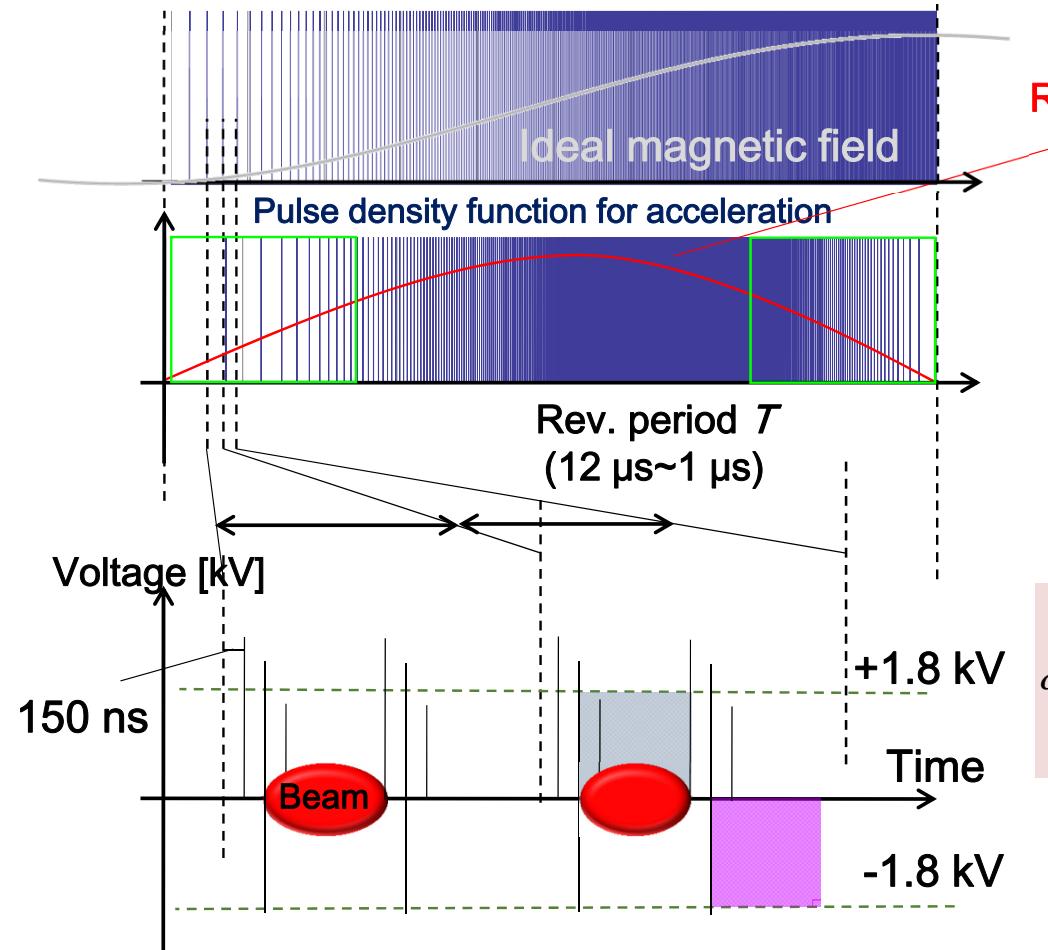
Here,
 ratio of charge to mass : Q/A
 charge element : e
 bending radius: ρ
 unit mass: m_0
 ideal magnetic field : $B(t)$

Conf. voltages are generated every turn.



How to generate acceleration voltage

Reference signals (signals of ideal rev. period) : $12 \mu\text{s} \rightarrow 1 \mu\text{s}$



Required acc. voltage per turn $V(t)$:

$$V(t) = \rho C_0 \frac{dB(t)}{dt}$$

ρ : bending radius
 C_0 : circumference
 $B(t)$: ideal magnetic field

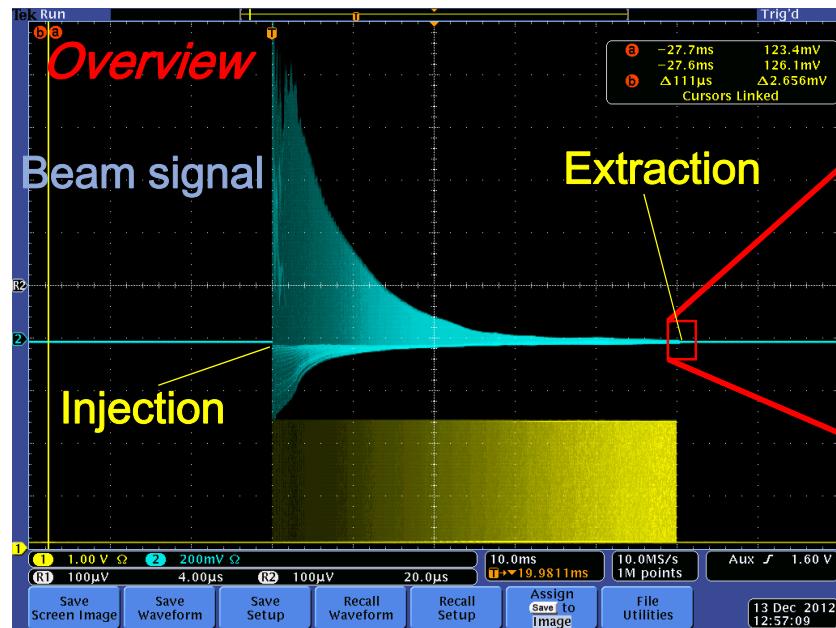
$$\delta(N+1) = \begin{cases} 1 & \cdots \left(\sum_{n=1}^{N+1} V(n) - V_0 \sum_{n=1}^N \delta(n) \right) > V_0 \\ 0 & \cdots \left(\sum_{n=1}^{N+1} V(n) - V_0 \sum_{n=1}^N \delta(n) \right) < V_0 \end{cases}$$

V_0 : constant induction acc. voltage
 $\delta(n)$: acc. density table
 N : turn number

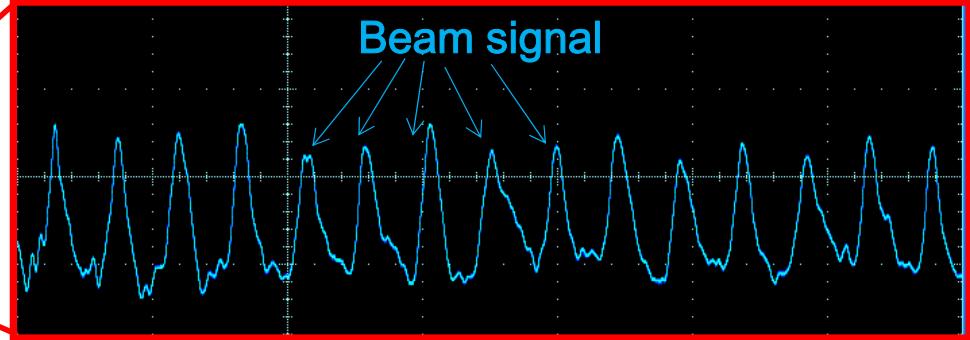
Induction acc. voltages are generated discretely in order to give required acc. voltage spuriously.

→ Pulse density control

Result of beam acceleration



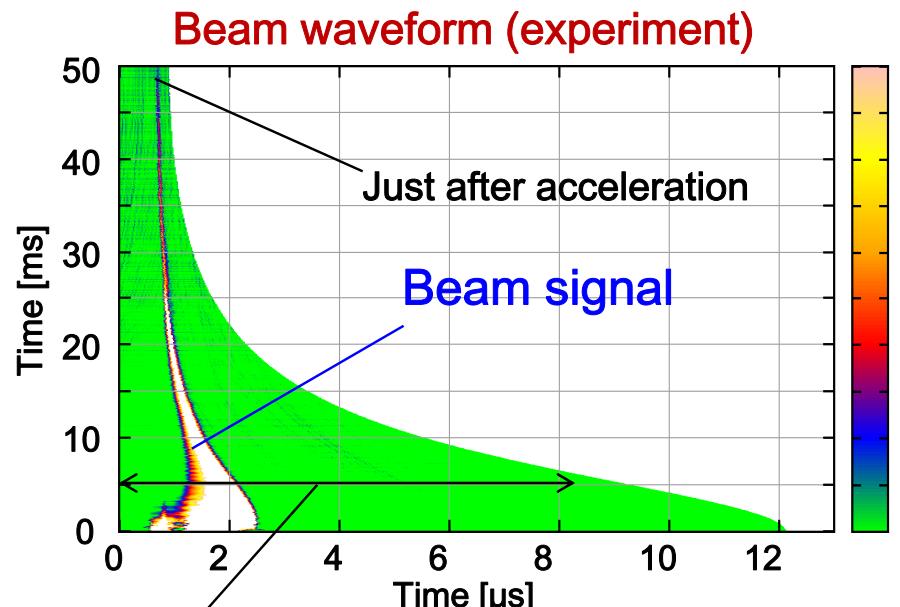
Zoom-up view (End of acceleration)



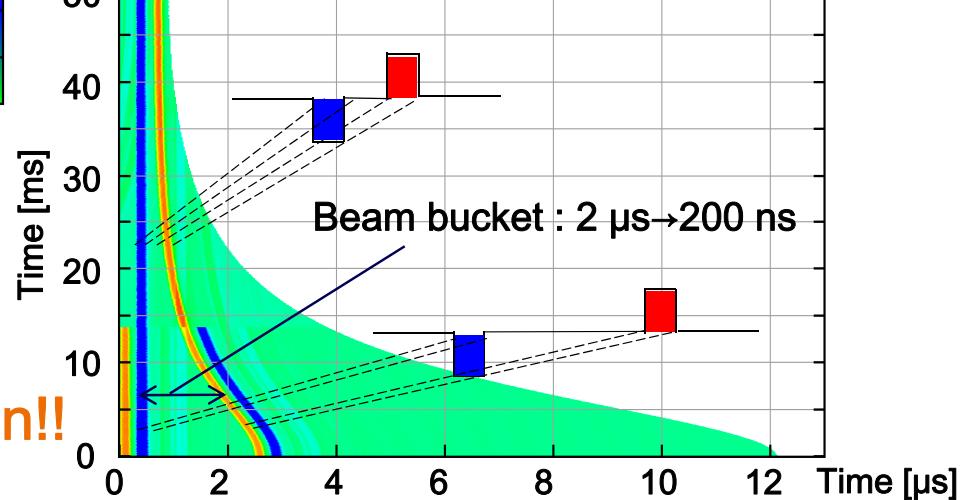
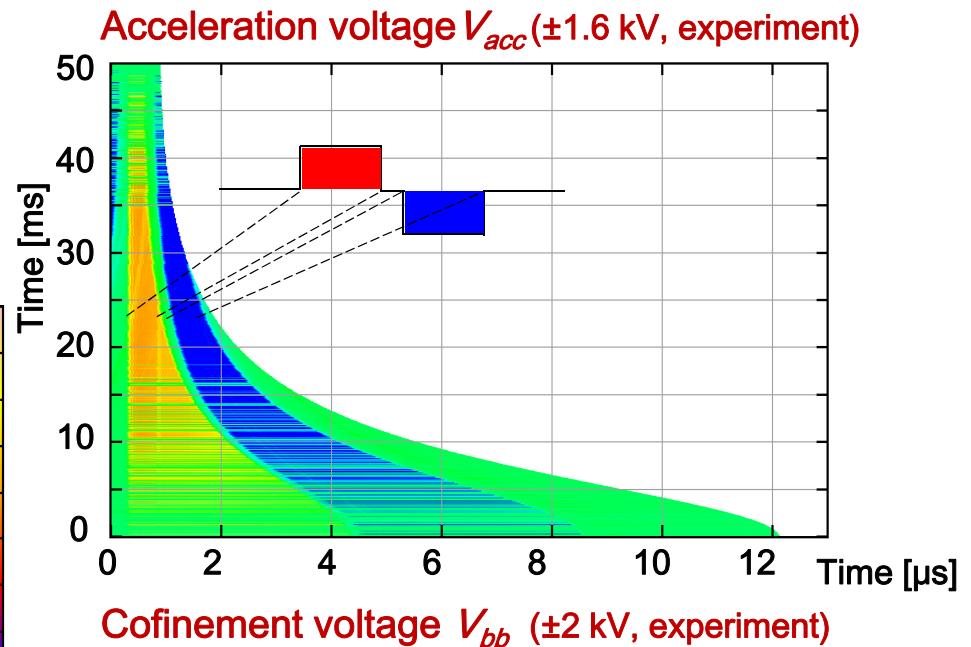
Beam and machine parameters:

Bending magnetic flux density	0.039 → 0.51 [T]
Mass to charge ratio A/Q	4/1
Energy	0.05→8 [MeV/u]
Injection current	~100 μ A

Wide-band acceleration (experiment)



Rev. period: $12 \mu\text{s} \rightarrow 1 \mu\text{s} !!$



Success of wide-band acceleration!!

Beam survival & discussion

Beam survival: ~ 10%

Reasons

- **Vacuum ($\sim 10^{-6}$ Pa)**

Strong interaction with residual gas in low energy (200 keV ~)

- **Non-zero dispersion optics (D = 1.4 m at Induction cell region)**

Unfortunately, present optics was designed for the PS booster ring 40 years ago.

- **Discrete acceleration**

In our case, acc. voltages are constant because of fixed output of DC power supply.
Therefore we do not generate acc. voltage every turn.

Solution:

DC power supply with time varying output voltage
may be ideal to meet required acceleration voltage demand.

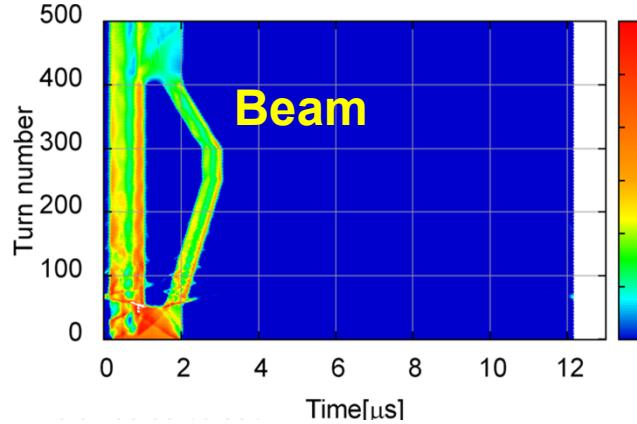
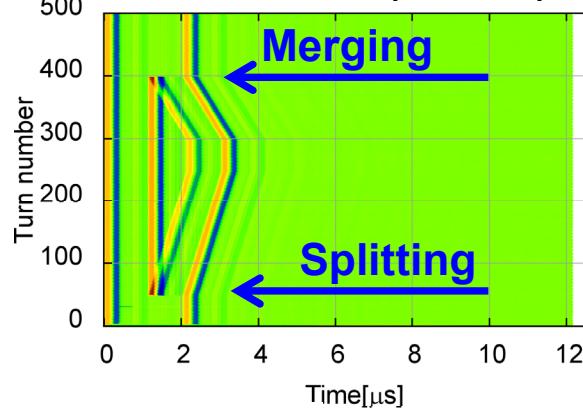
**These three reasons are not issues
for brand-new future induction synchrotrons.**

Novel beam handling (Experiment, E = 200 keV, A/Q = 4)

※ preliminary experiment

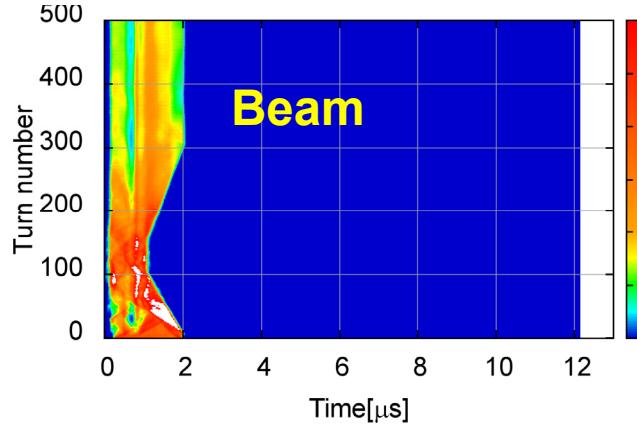
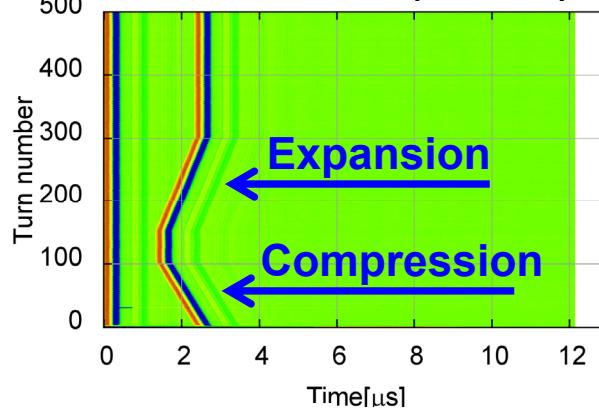
Splitting & Merging

Beam bucket (± 1.5 kV)



Compression & Expansion

Beam bucket (± 1.5 kV)



Combination of these techniques makes various operations.

Ex. 1: Separated beams can be provided to different lines at different energies.

Ex. 2: It is easy to stack bunches at injection.

Conclusion

We have demonstrated:

- **wide-band acceleration** (Rev. f : 82 kHz ~ 1 MHz)
A wide variety of ion species can be provided in a broad energy range for various applications, where high intensity is not required.
There is space charge limit in low energy !!
- **beam handling** techniques with induction synchrotron.
Various useful operations are expected soon.

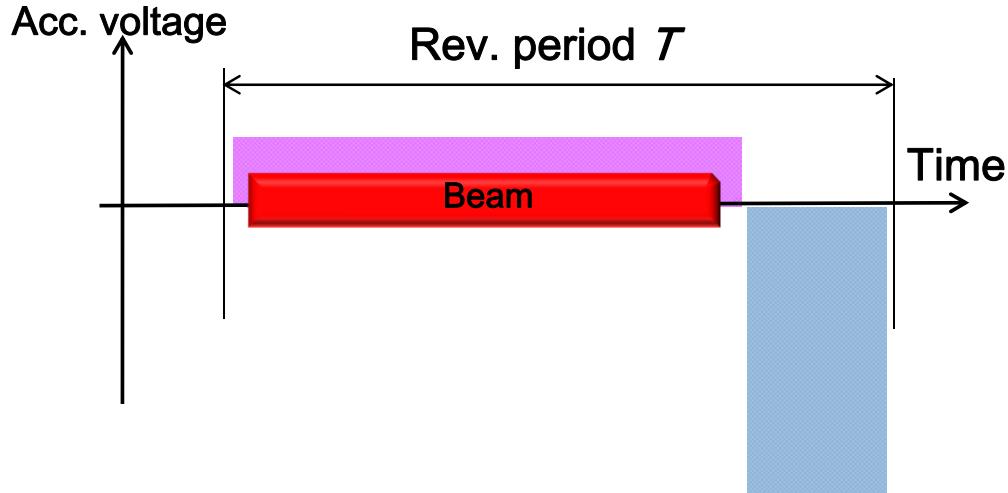
Future works ...

We try to establish the super bunch (very long beam) acceleration.

Thank you for attention !!

Preparatory Slides

Super bunch (very long beam) acceleration



Method 1: Half Bridge SPS

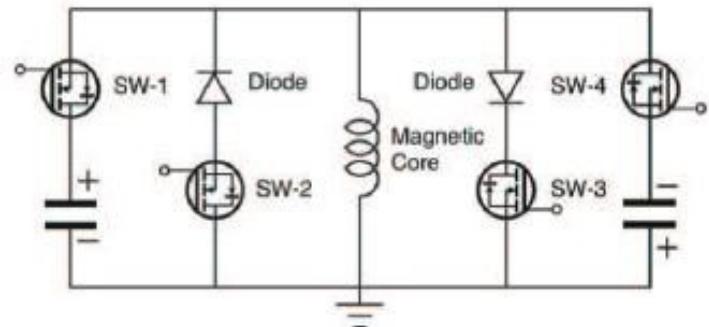
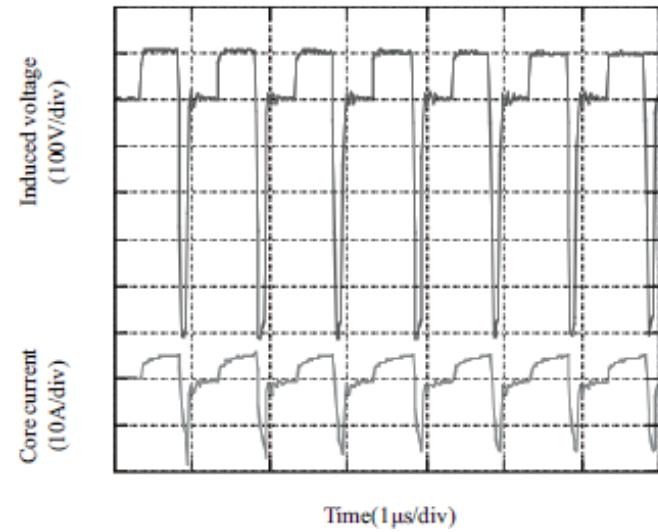
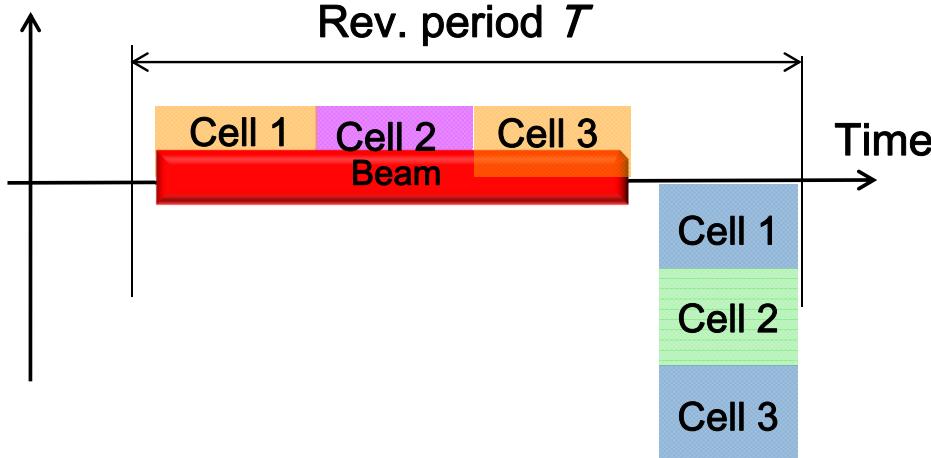


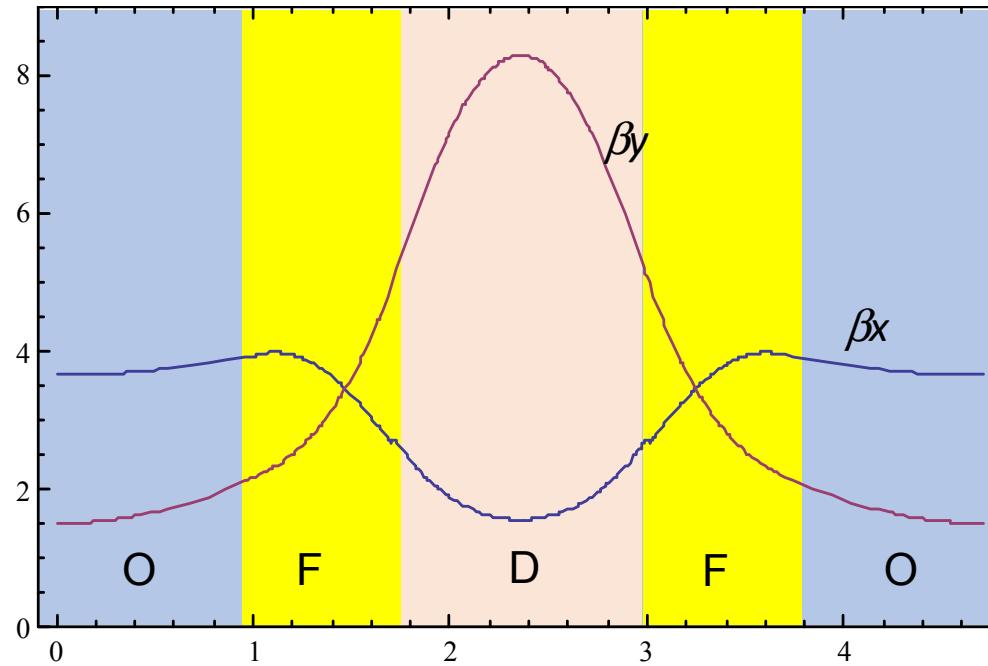
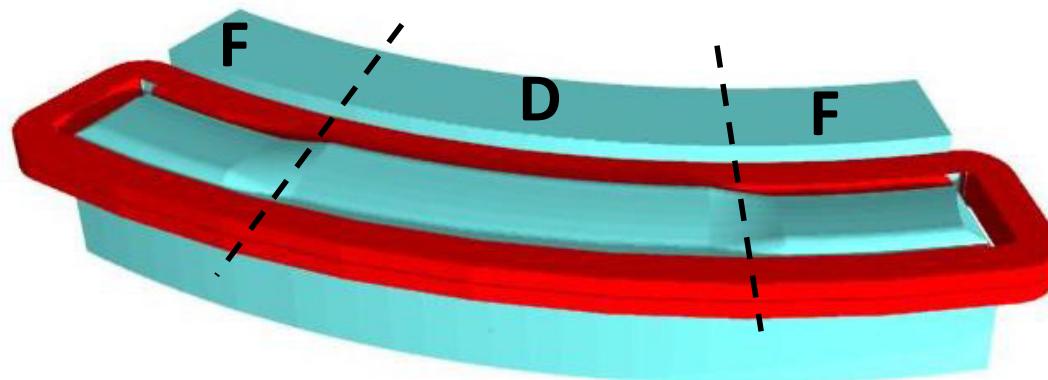
Fig. 11.16. Half bridge modulator.

Method 2: combined acceleration pulse



(experimental demonstration
by Dr. Watanabe of Tokyo Tech.)

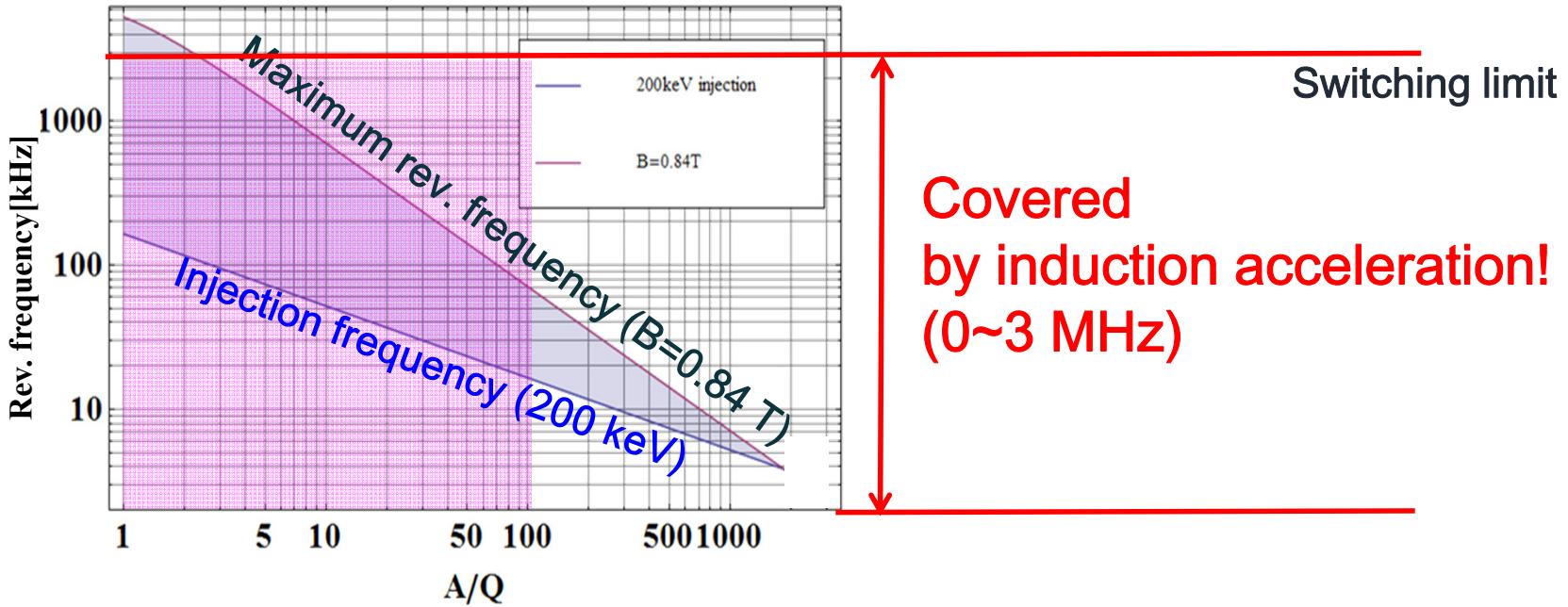
The ring lattice in the KEK digital accelerator



Which ion species can be accelerated ?

- ◆ Mass-to-charge ratio of many ions are $1\sim 100$.

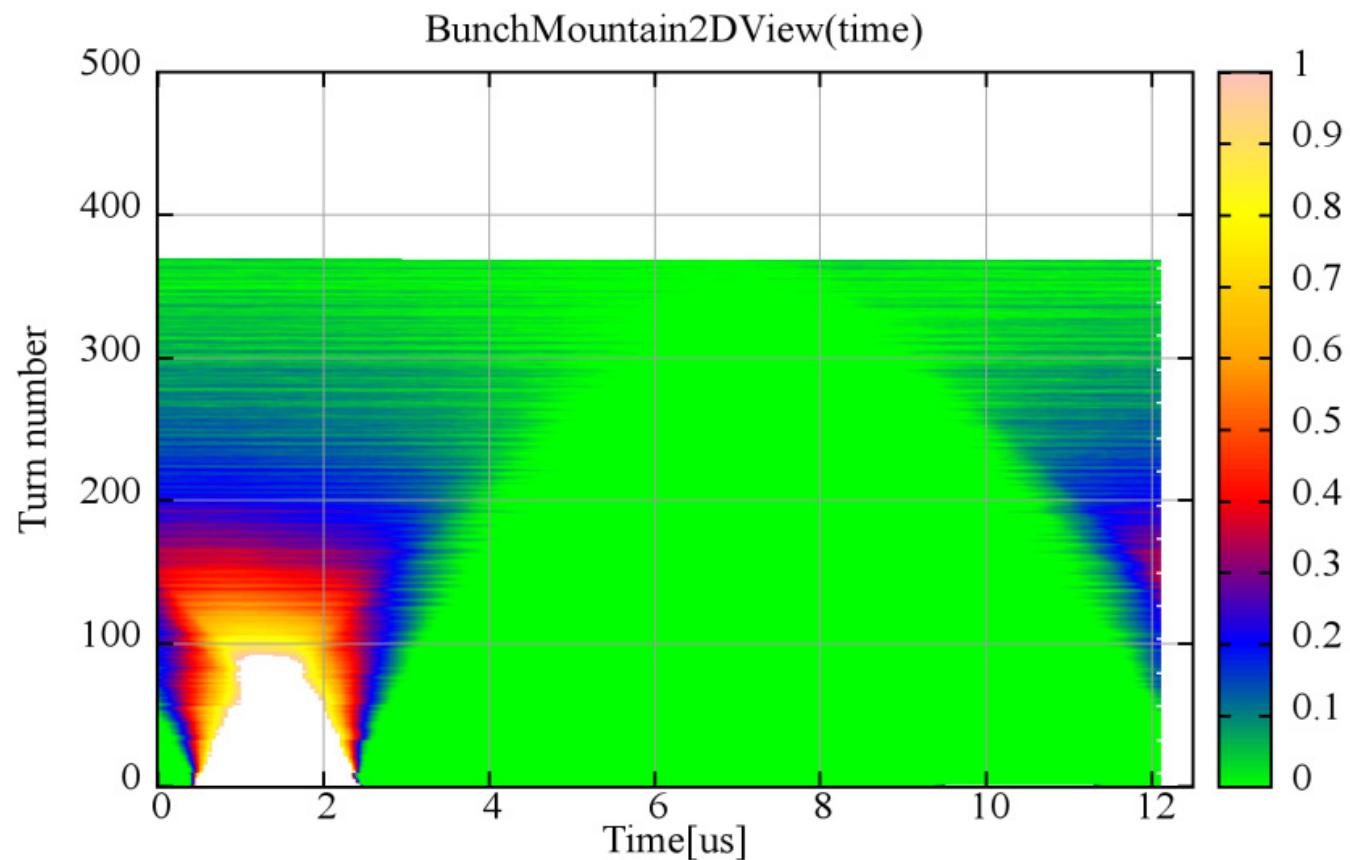
→ Most ions species with any charge state can be directly accelerated.



- ◆ Semiconductor switching capability of induction system limits maximum revolution frequency.

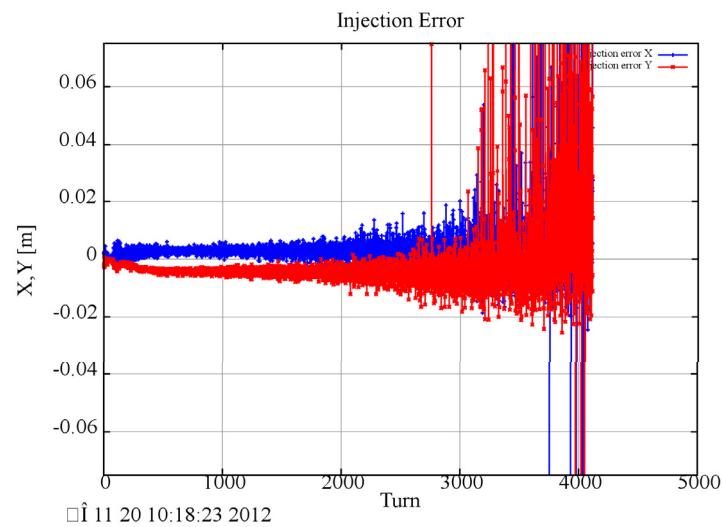
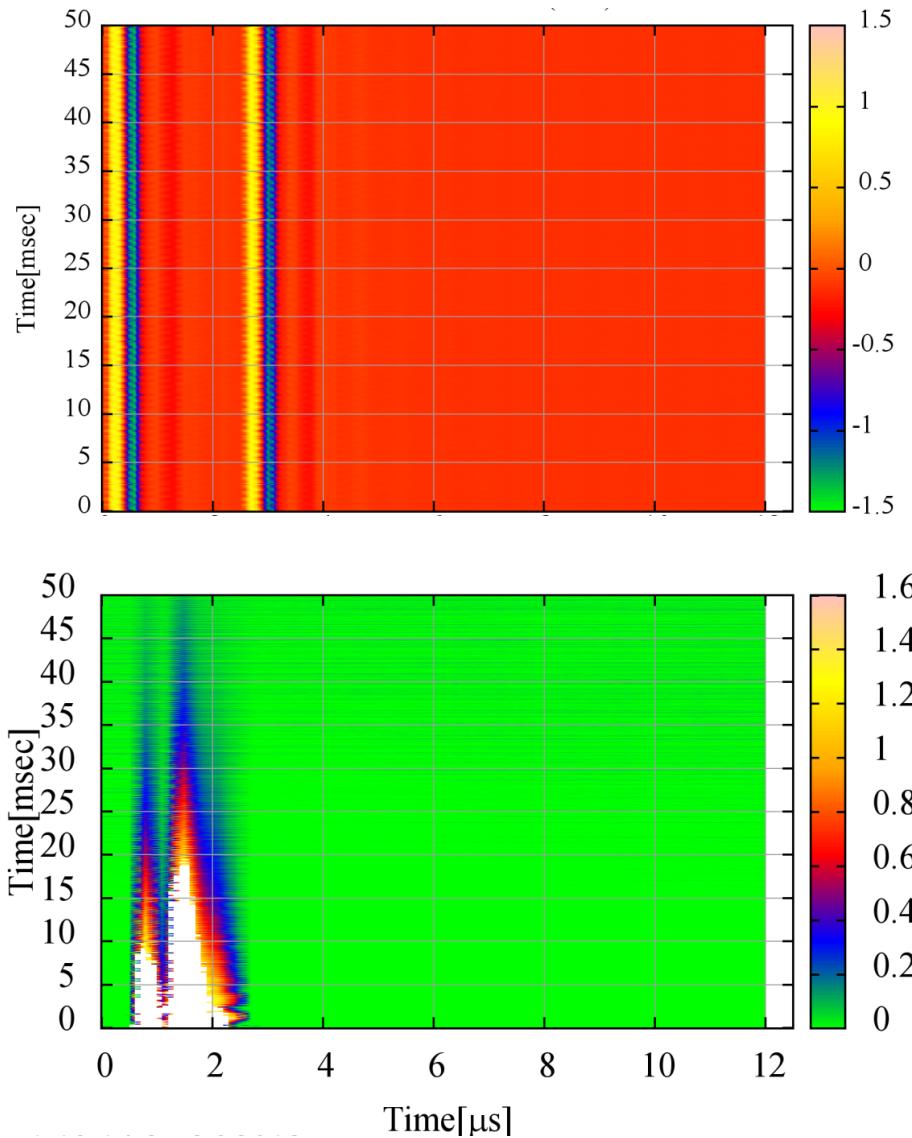
→ In principle, large scale ring can eliminate this problem.

Free running (200keV A/Q = 4)

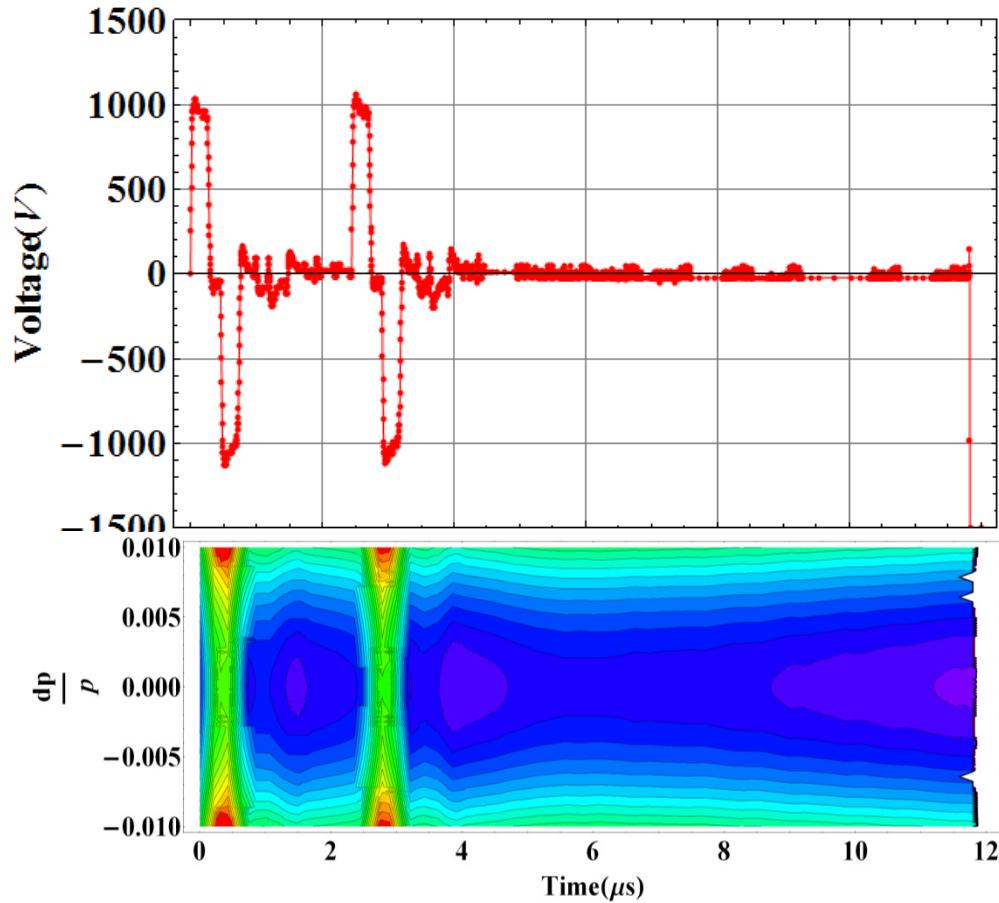


□ 11 13 15:16:09 2012

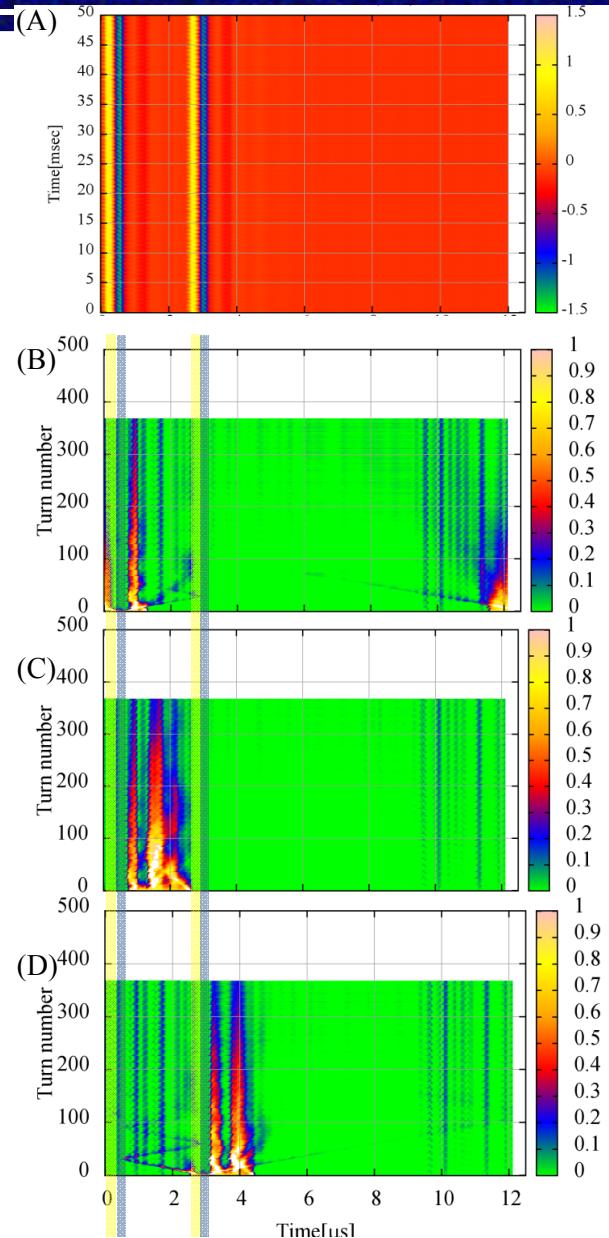
The Optimization of the barrier bucket position



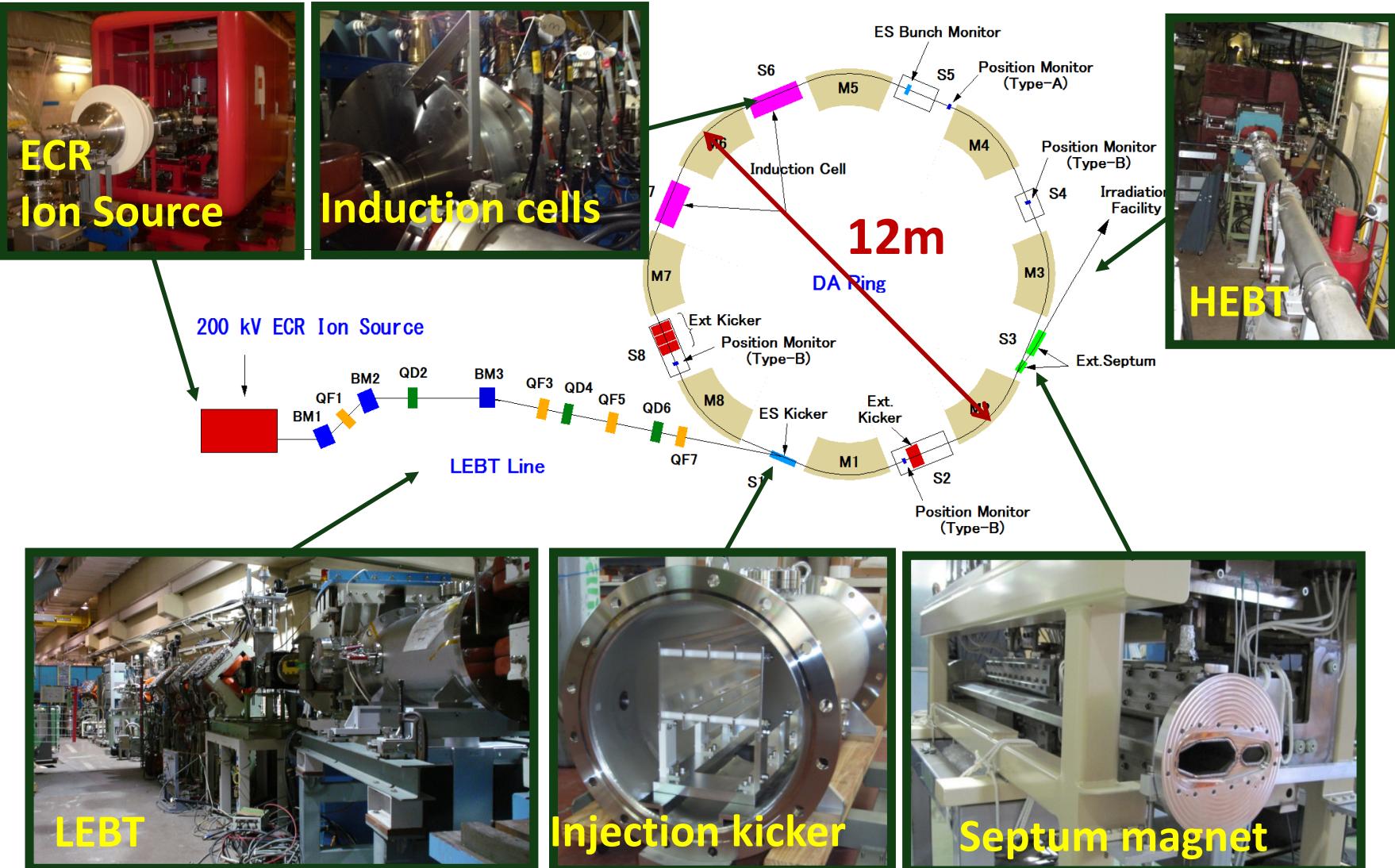
The Optimization of the barrier bucket position



$$H\left(\frac{dp}{p}, t\right) = \frac{\eta E_s \beta_s^2}{2} \left(\frac{dp}{p_s}\right)^2 + \frac{Z}{h \cdot T} \int_0^t V(t') dt'$$

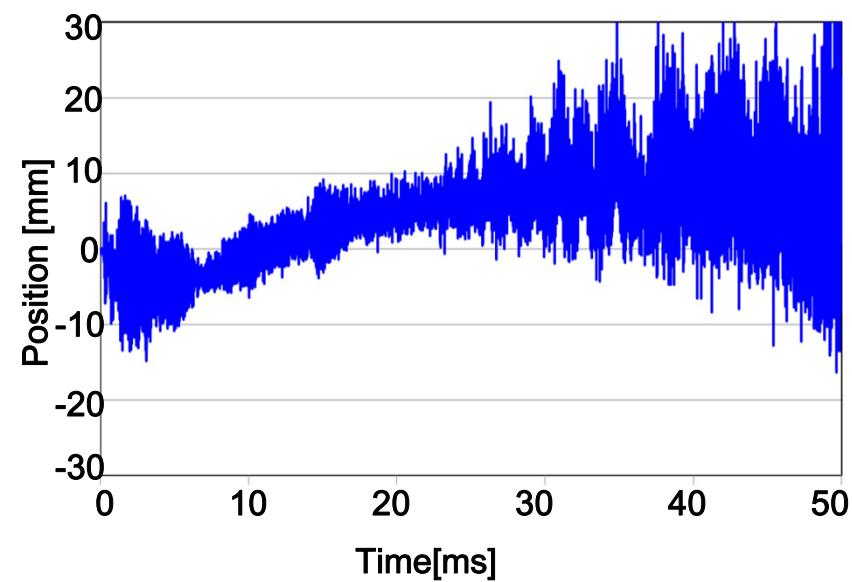


The Overview of KEK digital accelerator

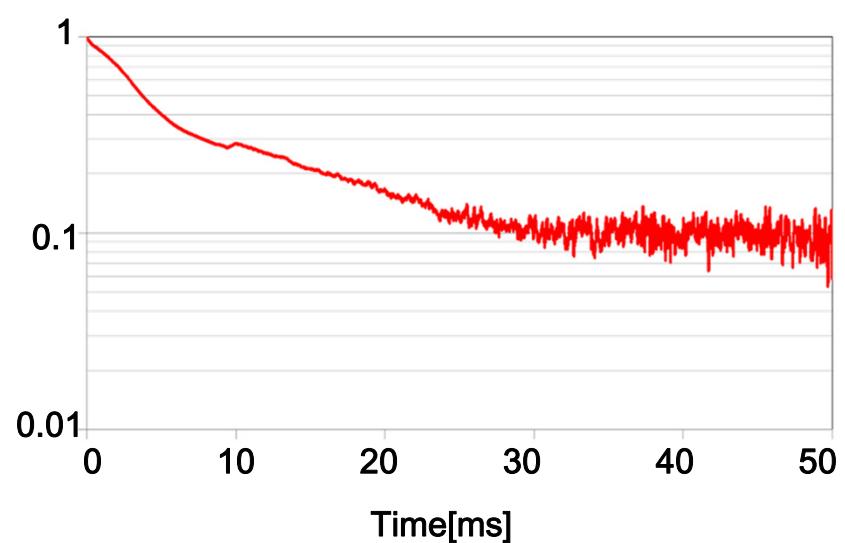


ビーム加速の解析結果 1

Horizontal beam position

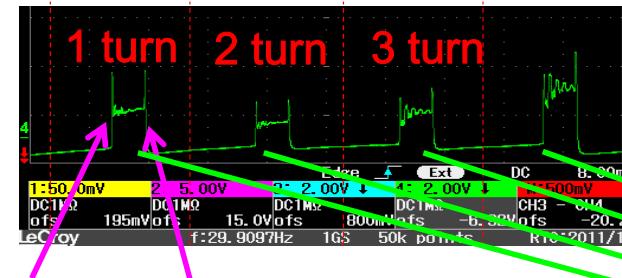


Beam survival: ~10%



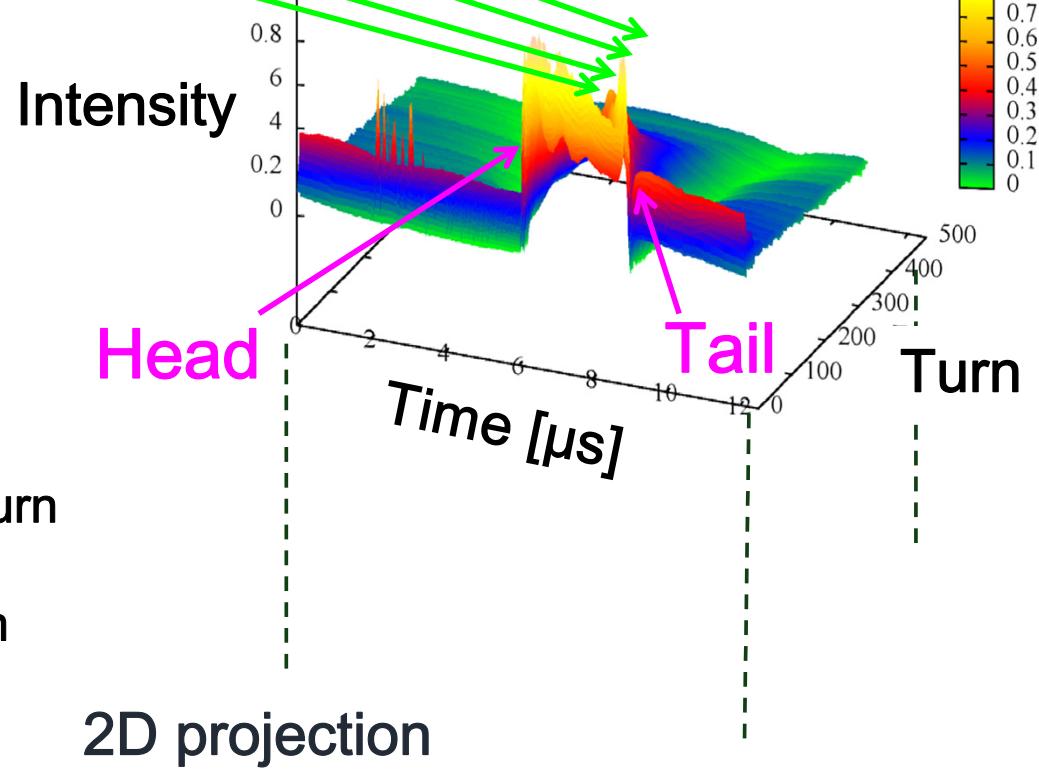
How to make mountain view

Monitor signal:



Head Tail

Mountain view:



Process:

1. Slicing oscilloscope view every ideal period
2. Arranging each graph in turn
3. Making 2D projection from the combined 3D graph

Adapting fully predictive control

It is difficult to construct feedback control because of the low S/N ratio of beam signal at present condition.

Method:

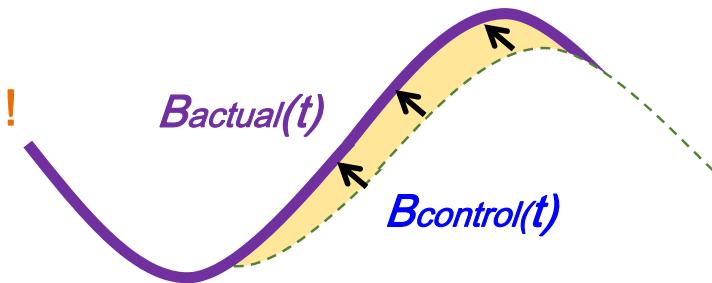


1. We set ideal magnetic flux density $B_{control}(t)$, calculate all required ideal periods and acceleration timings and write them in FPGA in advance.
2. We can modify ideal magnetic field $B_{control}(t)$ to correspond actual magnetic field $B_{actual}(t)$ from beam motion.

Actual magnetic field Ideal magnetic field

$$B_{actual}(t) = B_{control}(t) \Leftrightarrow \begin{cases} B_{actual_max} = B_{control_max} & (\text{Max. B}) \\ B_{actual_min} = B_{control_min} & (\text{Min. B}) \\ \delta = 0 & (\text{Phase difference}) \end{cases}$$

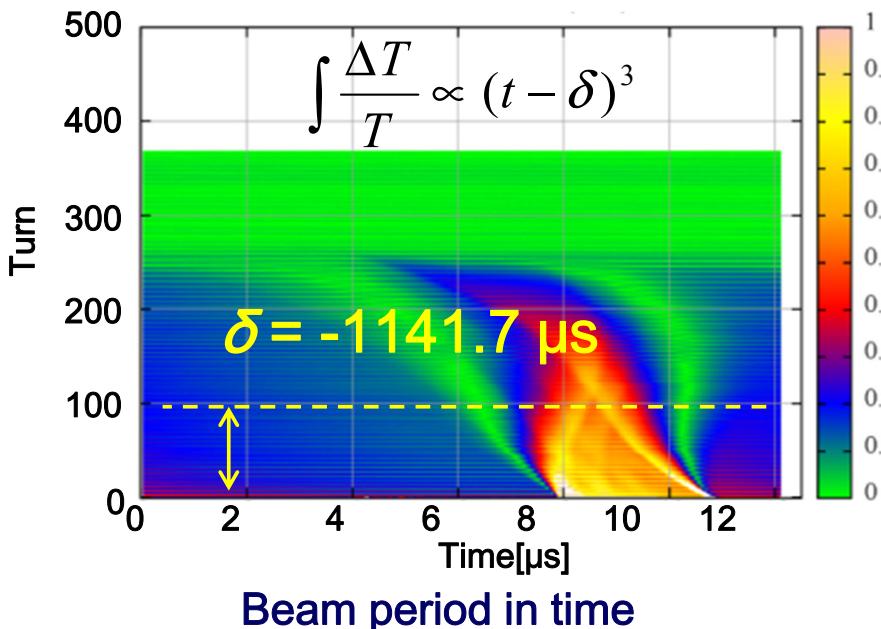
It is essential for beam acceleration
that Both magnetic fields are corresponded!!



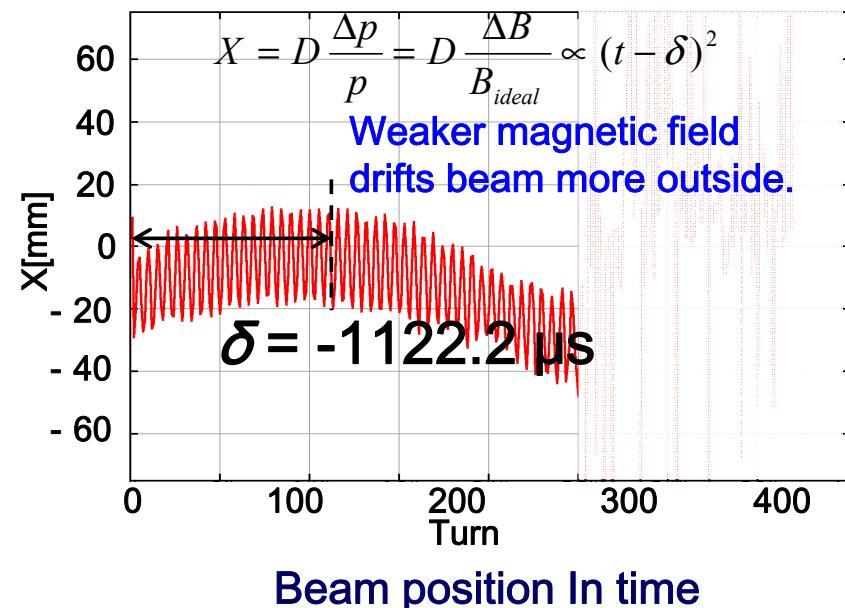
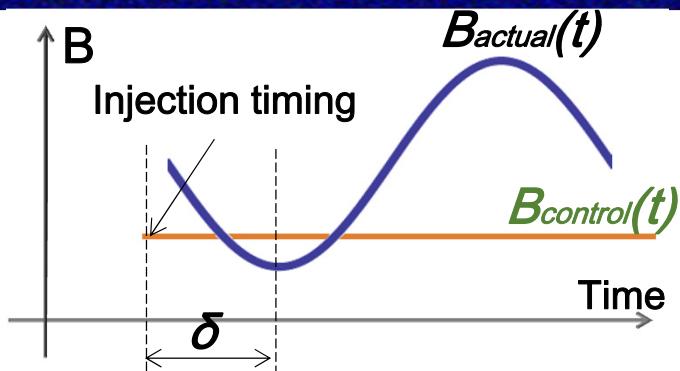
Minimization of phase difference δ between ideal and actual magnetic field (Free running)

Method:

1. Injecting beam quite before actual injection timing arbitrary
2. Observing horizontal beam position and beam period in time



Beam period in time



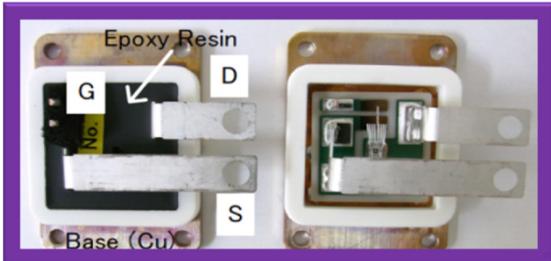
Beam position In time

Using this method, we can minimize phase difference δ
with the precision under one rev. period.

Development of Switching Power Supply (SPS)

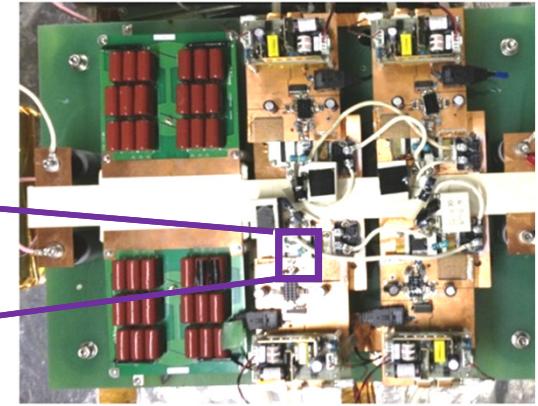


1st Gen.: 0.7 kV Si-MOSFET board

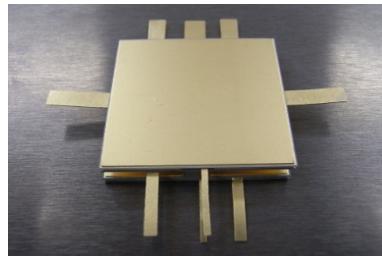


2nd Gen.: 1.2 kV SiC-JFET (custom package)

1st GEN. SPS(7 MOSFETs in series)



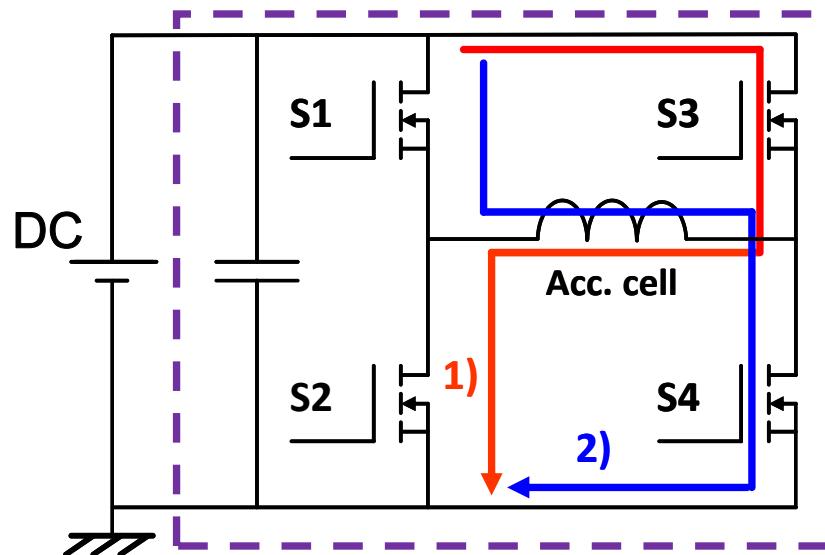
2nd Gen.: SPS



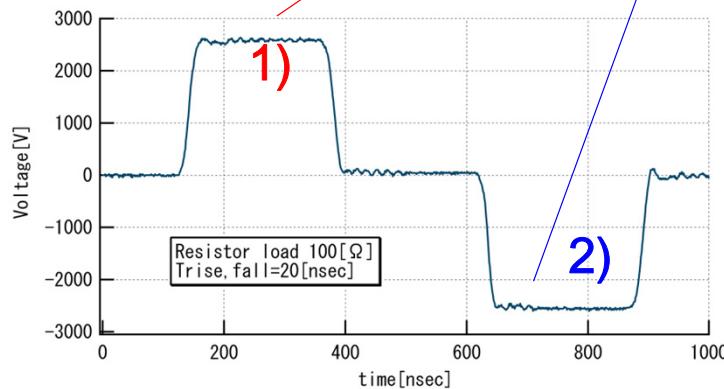
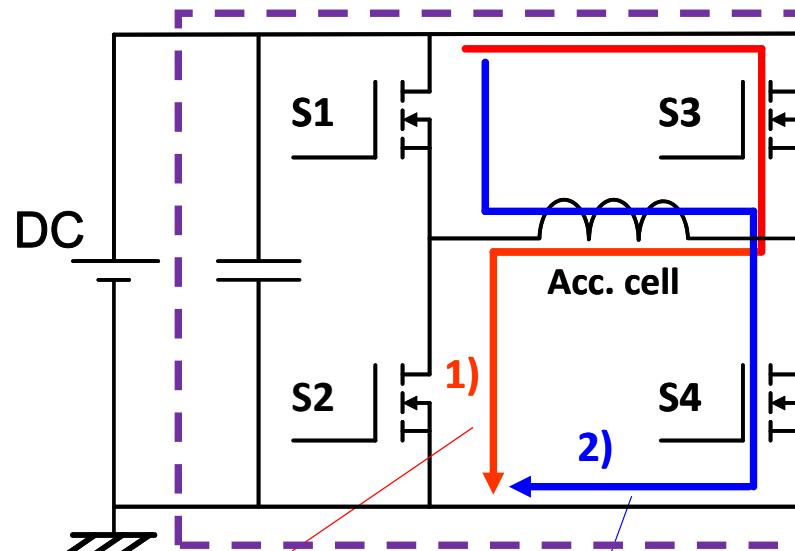
3rd Gen. 2.4 kV (custom package)

K.Okamura, et al , MOPME068 in IPAC'14

4th Gen. :3.3 kV SiC-MOSFET in 2015

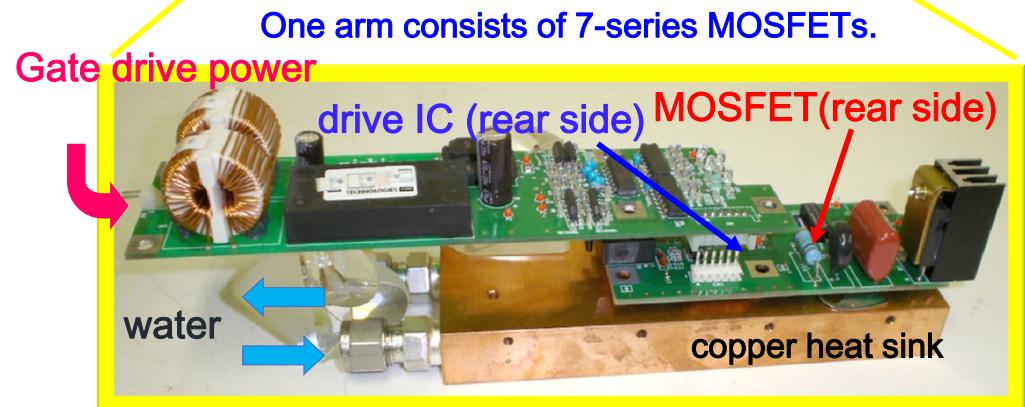
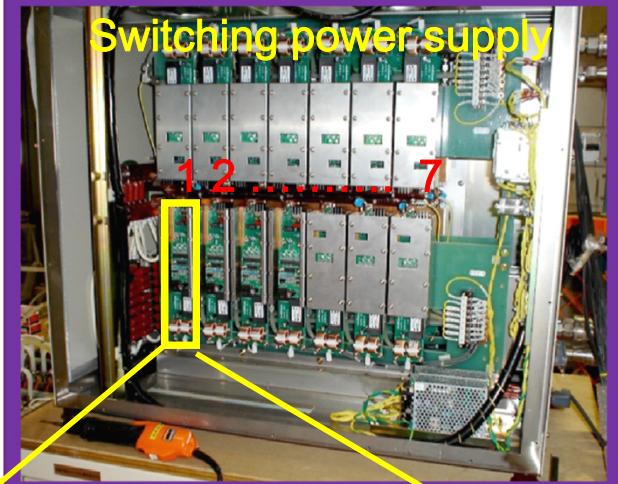


Switching Power Supply for Induction cells



Waveform generated by switching power supply
(2.5kV, 20A, 1MHz)

Switching power supply



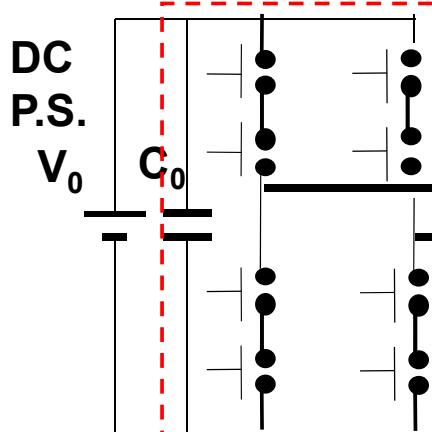
Next generation of SPS: K.Okamura, *et al.*, MOPME068 in IPAC'14
"SiC-JFET Switching Power Supply toward for Induction Ring Accelerators"

Possible Questions

- Applications of heavy ions delivered from the KEK-DA?
- Applications as an accelerator technology?
- How is wake fields serious in an induction synchrotron?
(What happens in high intensity drivers based
on induction acceleration?)
- How is noise problem overcome?
(Induction synchrotron is a fully pulse machine.)

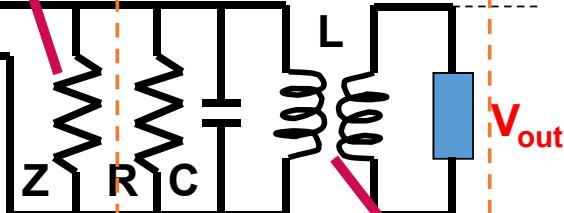
KEK Evolutional Induction Acceleration System

Switching power supply



Matching register

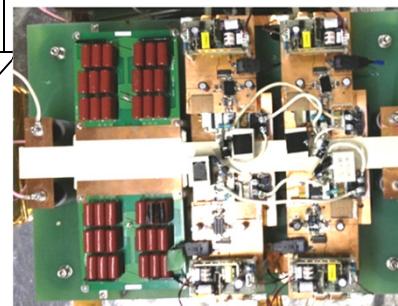
Induction cell



Primary terminal



Switchingarm S1
(7 MOSFETs in series)



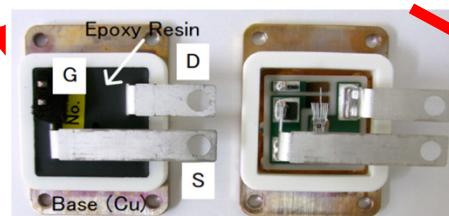
4th Gen.
3.3 kV SiC-MOSFET
in 2015

K.Okamura, et al ,
MOPME068
in IPAC'14

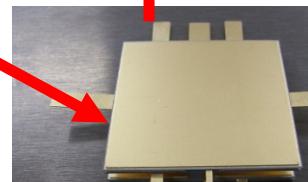
2nd Gen.
SPS and
1.2 kV SiC-MOSFET
(custom package)

Magnet material
nanocrystalline

1st Gen.: 0.7 kV Si-MOSFET board



3rd Gen. 2.4 kV (custom package)



Stack of 4 cells
 $V_{out}=3$ kV/cell